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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Masamichi NAKASHIBA et al

Serial No. 09/589,388

Filed June 8, 2000



Docket No. 2000_0722

Group Art Unit 3723

Examiner G. Nguyen

APPARATUS FOR AND METHOD FOR
POLISHING WORKPIECE

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEE FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0976.

AMENDMENT

Assistant Commissioner for Patents,
Washington, D.C.

Sir:

In response to the Office Action of June 21, 2001, please amend the above-referenced U.S. patent application as follows:

In the Claims:

Please add the following new claims:

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for
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73.(NEW) A polishing apparatus for polishing a surface of a workpiece,
comprising:
a top ring for holding a workpiece; and
a plurality of chambers formed in said top ring, fluid pressures being
supplied in said respective chambers to provide polishing pressure to a central area and
an outer circumferential area of the workpiece, wherein a radial width of said outer
circumferential area is narrower than that of said central area.

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